

FORM PTO 1449 (modified)			ATTY DOCKET NO. 3230-86	APPLICATION NO. 10/781,892			
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			APPLICANT WU et al.				
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			FILING DATE February 20, 2004		GROUP 2811- 2891		
Date Submitted to PTO: JUNE 9, 2004							
U.S. PATENT DOCUMENTS							
OLP EXAMINER INITIALS		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JUN. 9 2004							
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
AIKS		Y. Honda et al.; "Selective Area Growth Of GaN Microstructure On Patterned (111) and (001) Si Substrates"; <i>Journal of Crystal Growth 230</i> ; pp. 346-350; 2001					
		B. Beaumont et al; "Lateral Overgrowth Of GaN On Patterned GaN/Sapphire Substrate Via Selective Metal Organic Vapour Phase Epitaxy: A Route to Produce Self Supported GaN Substrates"; <i>Journal of Crystal Growth 189/190</i> ; pp. 97-102; 1998					
		Jaime A. Freitas, et al.; "Optical And Structural Properties Of Lateral Epitaxial Overgrown GaN Layers"; <i>Journal of Crystal Growth 189/190</i> ; pp. 92-96; 1998					
		Shuji Nakamura et al.; "Present Status Of InGaN/GaN/AIGaN-based Laser Diodes"; <i>Journal of Crystal Growth 189/190</i> ; pp. 820-825; 1998					
		Kazumasa Hiramatsu et al; "Selective Area Growth And Epitaxial Lateral Overgrowth of GaN by Metalorganic Vapor Phase Epitaxy and Hydride Vapor Phase Epitaxy"; <i>Materials Science and Engineering B59</i> ; pp. 104-111; 1999					
		Tsvetanka S. Zheleva, et al.; "Lateral Epitaxy and Dislocation Density Reduction in Selectively Grown GaN Structures"; <i>Journal of Crystal Growth 222</i> ; pp. 706-718; 2001					
		W. S. Wong et al.; "In XGa <sub>1-x</sub> N Light Emitting Diodes on Si Substrates Fabricated by Pd-In Metal Bonding and Laser Lift-off"; <i>Applied Physics Letters Volume 77; Number 18</i> ; pp. 2822-2824; 2000					
AIKS		Mitsuru Funato et al.; "Integration of GaN With Si Using a AuGe-Mediated Wafer Bonding Technique"; <i>Applied Physics Letters Volume 77; Number 24</i> ; pp. 3959-3961; 2000					
EXAMINER	Asst. Examiner Sarkar			DATE CONSIDERED		6/8/05	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.